

Attorney Docket: 061063-0306825

Client Reference: OSP-15115



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re PATENT APPLICATION of:

Confirmation Number: 5650

SHIOTA et al.

Group Art Unit: 1722

Application No.: 10/706,266

Filed: November 13, 2003

Examiner: Kunemund, Robert M.

Title: SILICON WAFER AND MANUFACTURING METHOD THEREOF

AMENDMENT WITH REQUEST FOR CONTINUED EXAMINATION
UNDER 37 C.F.R. §1.114

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the Office Action dated September 29, 2005, the period for reply being extended by the Petition for Three-Month Extension of Time filed herewith, prior to continued examination on the merits, please amend the above-identified application as follows: